

Supplementary Information

A high-performance TiO₂ protective layers derived from non-high vacuum technology for Si-based photocathode to enhance photoelectrochemical water splitting

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Fig. S1 Optical image for photoelectrochemical hydrogen evolution reaction device.

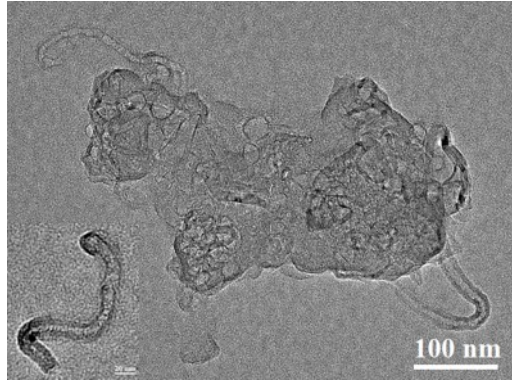


Fig. S2 TEM image of Co-NCNHP derived from ZIF-8@ZIF-67.

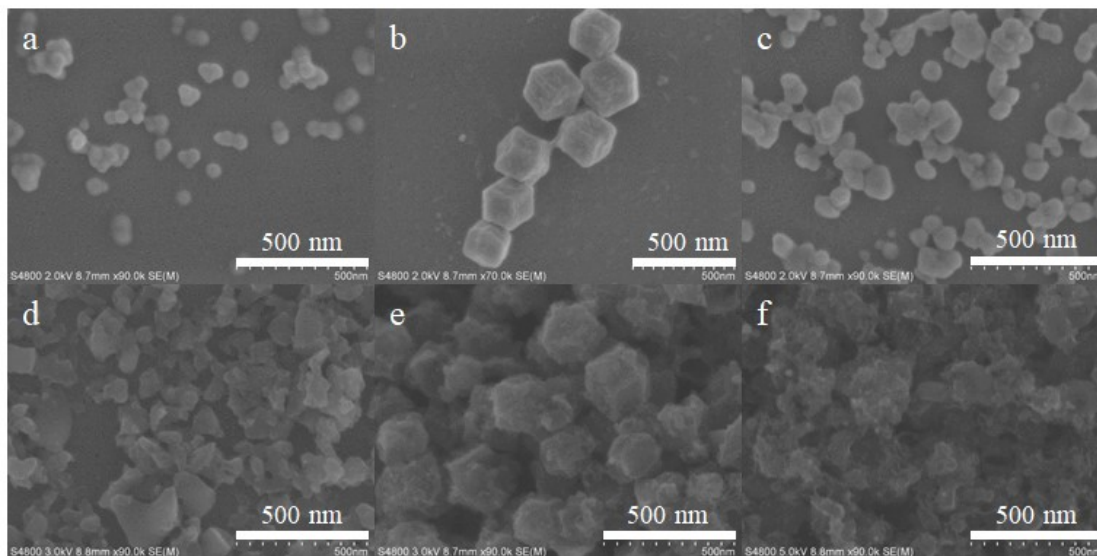


Fig. S3 SEM images of ZIF-8 (a), ZIF-67 (b), ZIF-8@ZIF-67 (c), ZIF-8-derived NCP (d), ZIF-67-derived Co-NCP (e) and ZIF-8@ZIF-67 derived Co-NCNHP (f).

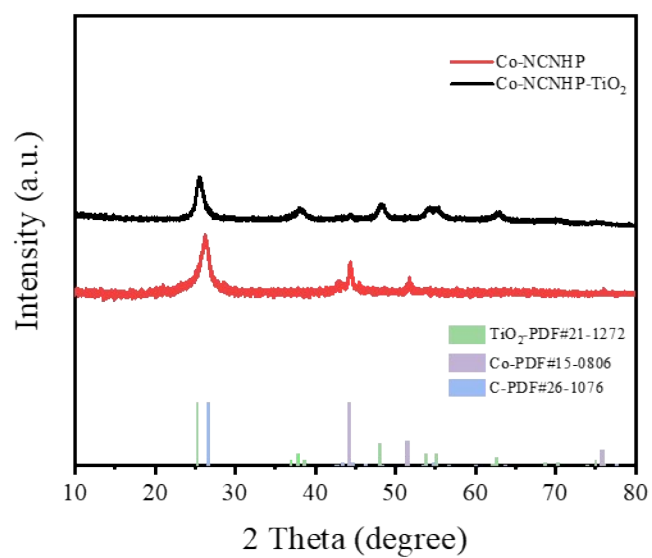


Fig. S4 XRD patterns of Co-NCNHP and Co-NCNHP-TiO₂.

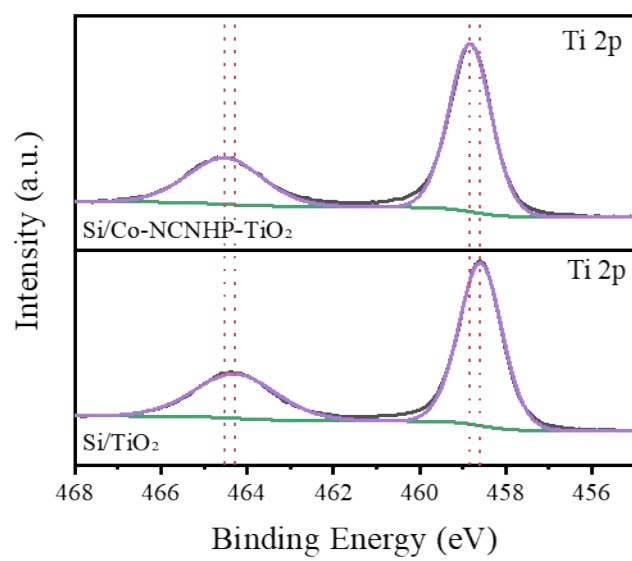


Fig. S5 High-resolution Ti 2p spectra of Si/Co-NCNHP-TiO₂ and Si/TiO₂.

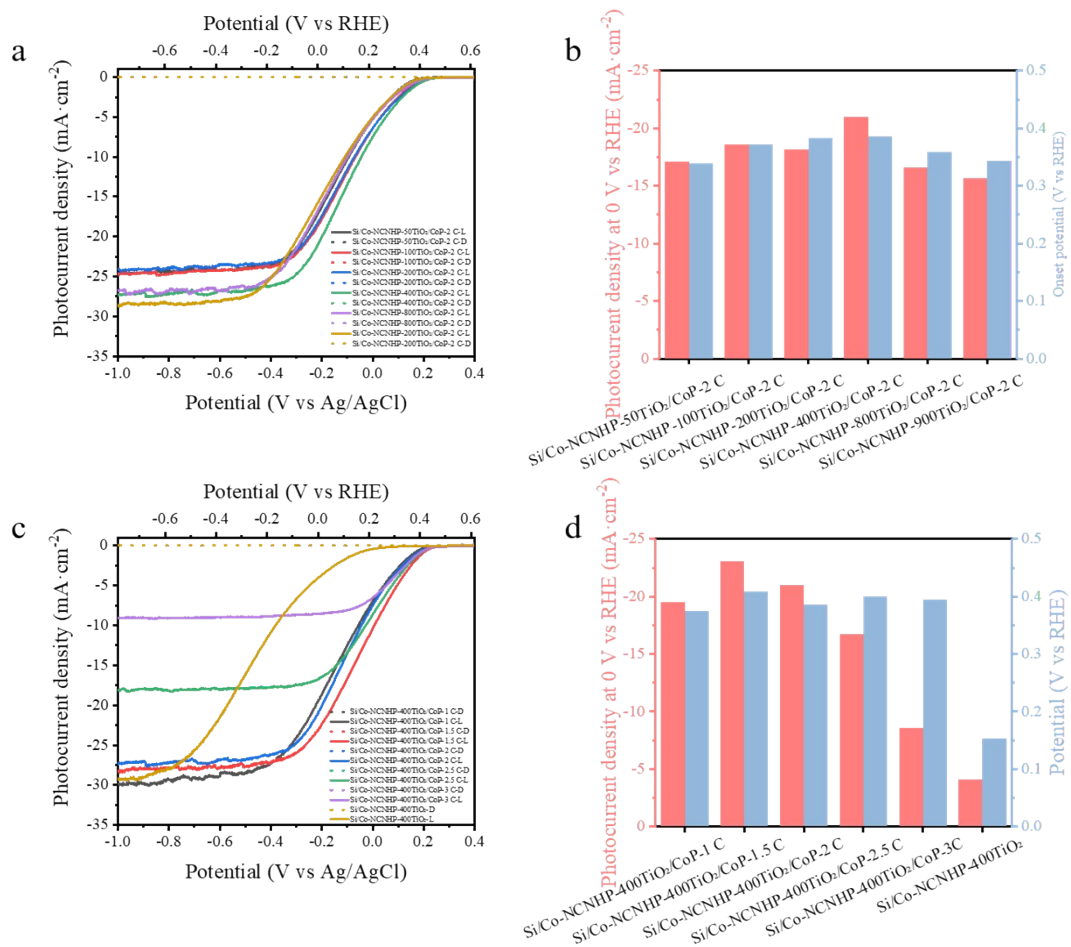


Fig. S6 LSV curves, onset potential and photocurrent density at 0 V vs RHE for samples with different Co-NCNHP to TiO₂ ratios (a, b) and CoP loadings (c, d) under 1 solar irradiation in 0.5 M H₂SO₄. Where # and & in Si/Co-NCNHP-# TiO₂/CoP-& C represent the volume ratio of Co-NCNHP dispersion to TiO₂ solution in the precursor of 1000-#: # and the charge density of CoP photodeposition (& C·cm⁻²), respectively. In this paper, if not otherwise specified, Si/Co-NCNHP-TiO₂/CoP is denoted as Si/Co-NCNHP-400TiO₂/CoP-1.5 C.

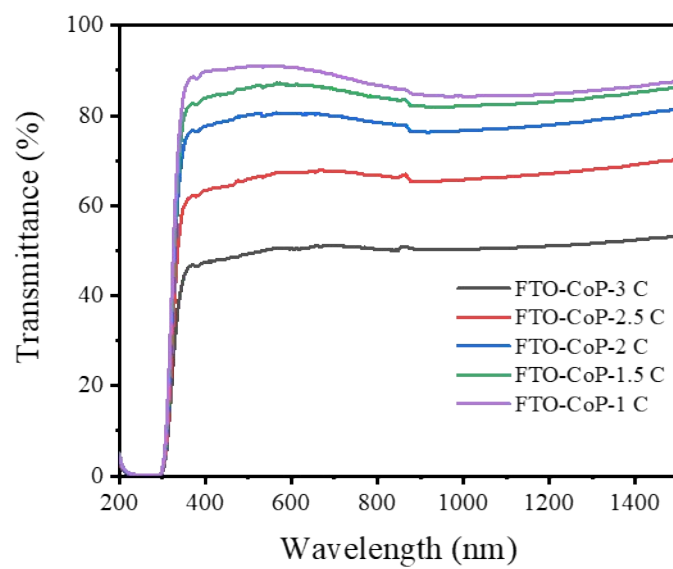


Fig. S7 Transmission spectra of different amounts of CoP loaded on FTO.

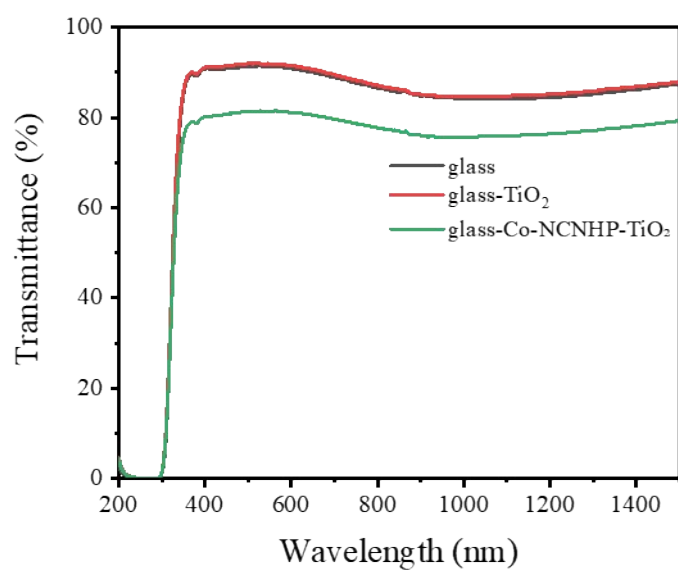


Fig. S8 Transmission spectra of glass, glass-TiO₂ and glass-Co-NCNHP-TiO₂.

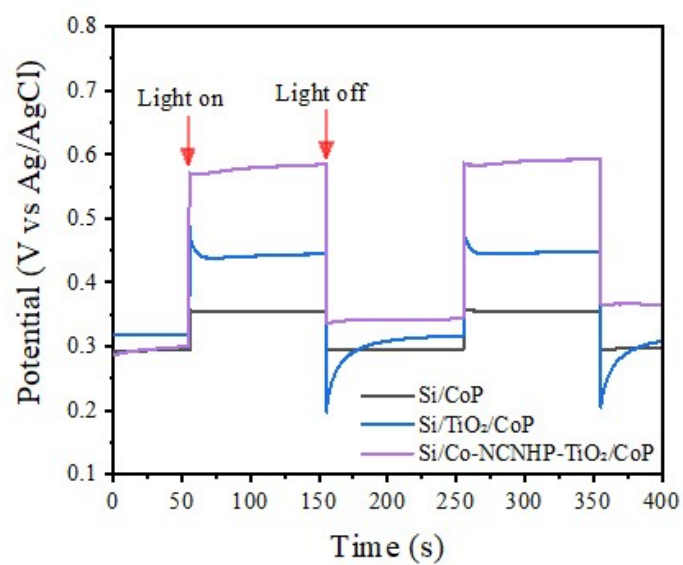


Fig. S9 Open circuit potential (OCP) measurements of Si/Co-NCNHP-TiO₂/CoP, Si/TiO₂/CoP, and Si/CoP photocathodes under chopped light irradiation. photovoltage: $V_{ph} = V_{light} - V_{dark}$.

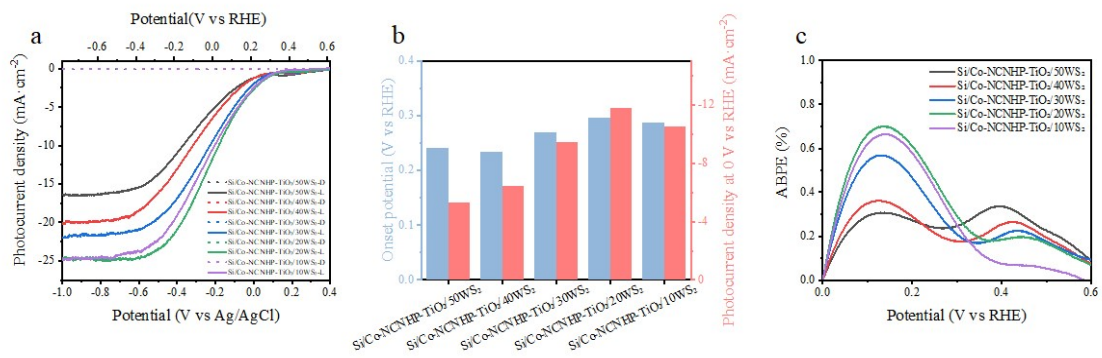


Fig. S10 (a) LSV curves, (b) onset potential and photocurrent density at 0 V vs RHE, (c) ABPE for samples with different WS₂ loading under 1 solar irradiation in 0.5 M H₂SO₄. Where ξ in Si/Co-NCNHP-TiO₂/ ξ WS₂ represents the concentration of (NH₄)₂WS₄ in the precursor solution (ξ mM). In this paper, if not otherwise specified, Si/Co-NCNHP-TiO₂/WS₂ is denoted as Si/Co-NCNHP-TiO₂/20WS₂.

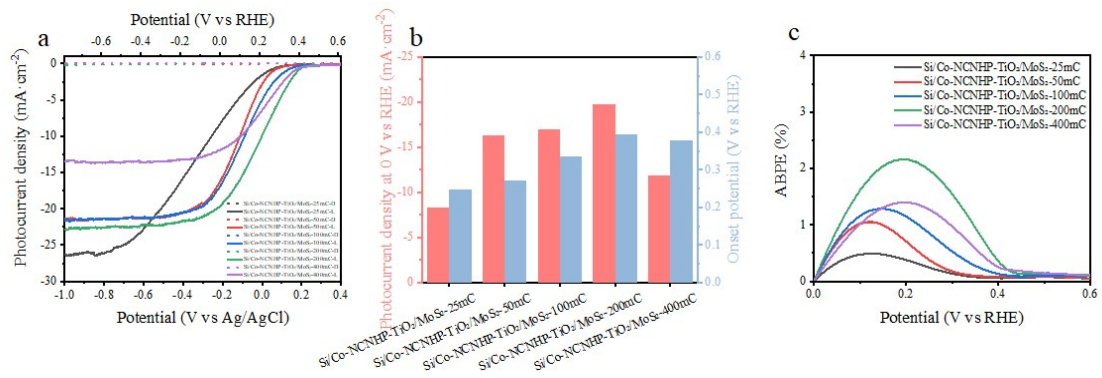


Fig. S11 (a) LSV curves, (b) onset potential and photocurrent density at 0 V vs RHE, (c) ABPE for samples with different MoS₂ loading under 1 solar irradiation in 0.5 M H₂SO₄. Where ※ in Si/Co-NCNHP-TiO₂/MoS₂-※ mC represents the charge density of CoP photodeposition (※ mC/cm²). In this paper, if not otherwise specified, Si/Co-NCNHP-TiO₂/MoS₂ is denoted as Si/Co-NCNHP-TiO₂/MoS₂-200 mC.

Table S1 R , R_s , R_{ct1} and R_{ct2} of Si/Co-NCNHP-TiO₂/CoP, Si/Co-NCNHP-TiO₂, Si/TiO₂/CoP, Si/TiO₂ and Si/CoP.

	R_s (Ω)	R_{ct1} (Ω)	R_{ct2} (Ω)	R_{ct2}/R_{ct1}	R (Ω)
Si _p /CoP	6.23	8753	4512	0.52	13271.23
Si _p /TiO ₂	19.29	2254	3.287×10^{19}	1.46×10^{16}	3.29×10^{19}
Si _p /TiO ₂ /CoP	26.16	869.6	333.3	0.38	1229.06
Si _p /Co-NCNHP-TiO ₂	15.1	62.05	1177	18.97	1254.15
Si _p /Co-NCNHP-TiO ₂ /CoP	5.634	11.01	6.685	0.61	23.329

$R = R_s + R_{ct1} + R_{ct2}$, R_s represents the series resistance, R_{ct1} represents the charge transfer resistance between the heterogeneous interfaces inside the electrode, and R_{ct2} represents the charge transfer resistance between the electrode and the electrolyte.

Table S2 Summary of PEC performance of Si photocathodes coated with earth-abundant catalysts.

Photocathode	Onset potential (V vs RHE)	Photocurrent density at 0 V vs RHE (mA·cm ⁻²)	Stability	Electrolyte	Ref.
Si/Co-NCNHP-TiO₂/CoP	0.409	-23.04	144 h	0.5 M H₂SO₄	
Si/Co-NCNHP-TiO₂/WS₂	0.297	-11.7	120 h	0.5 M H₂SO₄	This work
Si/Co-NCNHP-TiO₂/MoS₂	0.395	-19.72	88 h	0.5 M H₂SO₄	
Si/TiO ₂ /NiO _x	0.42	- 1.48	>5 h	Phosphate buffer (pH=7.00)	[1]
Si/NiCoSe _x	0.25	-37.5	2 h	0.5 M H ₂ SO ₄	[2]
Si/TiO ₂ /MoS ₂	0.18	-10	>15 h	1 M KOH	[3]
n ⁺ p-Si/Al ₂ O ₃ /MoS ₂	0.4	35.6	120 h	1 M HClO ₄	[4]
Si/C/TiO ₂ /Ni-Mo	0.35	-17.87	2 h	1 M KOH	[5]
Si/TiO ₂ /MoS ₂	0.46	-33.7	150 h	0.5 M H ₂ SO ₄	[6]
Si/Ti/NiFe(1:4) LDH	0.3	-7	24 h	1 M KOH	[7]
Si/TiO ₂ /WP	0.27	-15	110 h	1 M KOH	[8]
n ⁺ p-Si/Ti/Co-W-S	0.36	30.4	144 h	1 M HClO ₄	[9]
Si-TiO ₂ -MoS ₂ /Rh-P	0.43	-24.1	>1 h	0.5 M H ₂ SO ₄	[10]
Si/CN/TiO ₂ /NiCoP	0.42	-19.87	3 h	1 M KOH	[11]
Si/MoS _{1.75} P _{0.25}	0.29	-23.8	2 h	0.5 M H ₂ SO ₄	[12]
Si/CuCl-Tu	0.15	-2.7	16 h	0.2 M phosphate buffer (pH~7)	[13]
n ⁺ p-Si/Ti/NiP ₂	0.41	12	6	0.5 M H ₂ SO ₄	[14]
Si/SnS ₂ /MoS ₂	0.23	-23.8	2.2	0.5 M H ₂ SO ₄	[15]

Not: The explanation of the relationship between reducing the light reflection and increasing the photocurrent density.

Generally, the PEC water splitting process is made up of the following three steps: 1) photoexcitation of electron-hole pairs in the semiconductor, 2) separation and migration of photoinduced electron-hole pairs, and 3) oxidation and reduction of surface water by photogenerated holes and electrons to produce O₂ and H₂, respectively. Meanwhile, a photon absorbed by semiconductor, which energy is greater than the band gap, can generate an electron-hole pair. Therefore, increasing the light absorption of semiconductor can generate more electron-hole pairs in the semiconductor. Equations for evaluating photocurrent density (J_{ph}) are as follows.

$$J_{ph} = J_{abs} \times \eta_{separation} \times \eta_{injection} \quad (S1)$$

$$J_{abs} = \frac{q}{hc} \int_{\lambda_1}^{\lambda_2} \lambda \varphi_{\lambda} \eta_{abs} d\lambda \quad (S2)$$

Where J_{abs} is the photon adsorption rate expressed as the photocurrent density, q is the charge of an electron, h is the Plank constant, c is the light speed, φ_{λ} is the photon flux of the AM 1.5 G solar spectrum, η_{abs} is the light absorption efficiency, $\eta_{separation}$ is the separation efficiency of photogenerated carriers, and $\eta_{injection}$ is the injection efficiency of photogenerated carriers into electrolyte. It can be seen from equations (S1) and (S2) that the photocurrent density is directly proportional to the light absorption. Therefore, the antireflective structure can increase the light absorption, and then enhance the photocurrent density.

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